

1201.65872



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent application of: )  
Applicant: Bohn et al. )  
Serial No.: 09/989,050 )  
Filed: November 20, 2001 )  
For: METAL ASSISTED CHEMICAL )  
ETCH TO PRODUCE POROUS )  
GROUP III-V MATERIALS )  
Art Unit: 1746 )  
Examiner: Unassigned )

I hereby certify that this paper is being deposited with  
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4/8/02  
Date  
F-CLASS.WCM  
Appr. February 20, 1998  
Registration No. 35132  
Attorney for Applicant

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INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

In accordance with 37 C.F.R. §§1.56, 1.97 and 1.98, Applicants through counsel  
herewith:

Submit copies of patents and publications as set forth in the attached form PTO-  
1449 as follows.

UNITED STATES PATENTS

| <u>Patent No.</u> | <u>Issued</u> | <u>Patentee(s)</u> |
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### **PUBLICATIONS**

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2. T. Monguchi, H. Fujioka, K. Ono, Y. Baba, M. Oshima, "Effects of Wet Etching on Photoluminescence of Porous Silicon", *Journal of The Electrochemical Society*, Vol. 147, No. 2, 2000, pp. 602-605.
  
3. J. Salonen, V.P. Lehto, M. Bjorkqvist, E. Laine, "A Role of Illumination During Etching to Porous Silicon Oxidation", *Applied Physics Letters*, Vol. 75, No. 6, August 9, 1999, p. 826-828.
  
4. T. Tsuboi, T. Sakka, Y. H. Ogata, "Chemical Etching of Porous Silicon in Diluted Hydrofluoric Acid", *Solid State Communications*, Vol. 109, 1999, pp. 195-199.

**REMARKS**

Applicants respectfully request that the Examiner consider the above-listed references in the examination of this application and list these references of record in the application.

Respectfully submitted,

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